

Attorney's Docket No.: 5353C1-459003  
Client's Ref. No.: 5353/CMP

**OFFICIAL COMMUNICATION**  
**FACSIMILE**  
**FOR THE PERSONAL ATTENTION OF:**  
**EXAMINER SYLVIA R. MACARTHUR**

**GROUP 1763 FAX NO: (703) 872-9630**

Number of pages including this page (38)

Applicant : Wallace T.Y. Tang  
Serial No. : 09/134,147  
Filed : August 14, 1998

Art Unit : 1763  
Examiner : Sylvia R. MacArthur

**FACSIMILE COMMUNICATION**

Title : IN-SITU REAL-TIME MONITORING TECHNIQUE AND APPARATUS FOR  
DETECTION OF THIN FILMS DURING CHEMICAL/MECHANICAL  
POLISHING PLANARIZATION

Commissioner for Patents  
Washington, D.C. 20231

Sir:

Attached to this facsimile communication cover sheet is a copy of the following documents:

- o Copy of Allowed Claims from Application Serial No. 07/996,817 as of termination of interference on 02/25/2002;
- o Copy of 1.312 Amendment filed with the Issue Fee for Application Serial No. 07/996,817;
- ~~o Copy of Allowed Claims from Application Serial No. 09/134,147;~~
- o Copy of Preliminary Amendment filed with the RCE for Application Serial No. 09/134,147;

faxed this 30<sup>th</sup> day of **January**, 2003, to Group 1763, the United States Patent and Trademark Office.

Please note that we are trying to obtain the PCT/Reasons Statement and will forward upon receipt.

Respectfully submitted,

Date: January 30, 2003

  
David J. Goren  
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Attorney's Docket No. 05542-459001 / 5353/CMP

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Wallace T.Y. Tang  
Serial No. : 07/996,817  
Filed : December 28, 1992  
Art Unit : 1763  
Examiner : Thi Dang  
Confirmation No.: 2081  
Notice of Allowance Date: August 6, 2002  
Title : IN-SITU REAL-TIME MONITORING TECHNIQUE AND APPARATUS FOR  
ENDPOINT DETECTION OF THIN FILMS DURING  
CHEMICAL/MECHANICAL POLISHING PLANARIZATION

**BOX ISSUE FEE**

Commissioner for Patents  
Washington, D.C. 20231

AMENDMENT UNDER 37 CFR 1.312

Please amend the application as issued below. This amendment is being filed concurrently with the payment of the issue fee.

In the Claims:

Please amend claims 59, 62, 68 and 82 as follows:

-- 59. (Amended) A method for producing a semiconductor device or a patterned layer intermediate, which comprises the steps of:

chemically mechanically polishing at least one layer on one side of the semiconductor device or patterned layer intermediate, wherein the layer is composed of a material selected from the group consisting of an insulating material, a semi-conducting material, a conducting material, and combinations thereof,

illuminating the side of the semiconductor device or patterned layer intermediate not being polished with light of a wavelength between about 1,000 nm and about 11,000

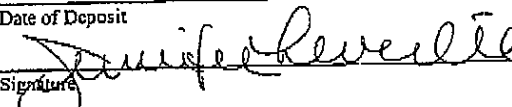
## CERTIFICATE OF MAILING BY FIRST CLASS MAIL

I hereby certify under 37 CFR §1.8(a) that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated below and is addressed to the Commissioner for Patents, Washington, D.C. 20231.

November 6, 2002

Date of Deposit

Signature



Jennifer Levell

Typed or Printed Name of Person Signing Certificate